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Effect of Sb₂Se on phase change characteristics of Ge₂Sb₂Te₅

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Abstract

In this paper, effect of Sb₂Se on phase change characteristics of Ge₂Sb₂Te₅(GST) are systemically studied for applications in phase-change random access memory (PRAM). The crystallization temperature of Sb₂Se-GST increases with the increasing Sb₂Se content, while the archival life of amorphous state firstly decreases and then increase. The phase transition from face-centered-cubic (FCC) to hexagonal(HEX) phase was suppressed when Se atomic percentage is larger than 9% for Sb₂Se-GST film. The widen band gap and high value of B^{1/2} lead to about five orders of magnitude of the resistance contrast between amorphous and crystalline states. Compared with GST, Ge₄Sb₅₂Te₉Se₃₅ shows high crystallization temperature, wider band gap and a fast switching speed, suggesting a potential candidate for PRAM.

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1. Introduction

Phase change memory (PCM) has attracted much attention due to its high speed, excellent scalability and good compatibility with complementary metal-oxide-semiconductor (CMOS) technology [1-3]. PCM utilizes the high resistance contrast between amorphous and crystalline states of phase change material to store information. GST is the most widely used phase change materials for its good comprehensive properties such as good trade-off between crystallization rate and thermal stability. However, there are several issues needed to be addressed for GST scaled down to a smaller dimension which is promising for future generations. High melting temperature (~620°C for GST) will cause a high RESET current in PCM devices, leading to higher power consumption[4]. Besides, low crystallization temperature(T_e , about 170°C) results in the thermal stability with 10-year data retention temperature at 85°C[5, 6] that is not ideal for the consumer products and automotive systems.

Many efforts are devoted to optimizing the data retention, high speed, and power of GST. Doping is one of the most effective ways to improve the property of PCM. For example, in order to enhance the data retention, many elements such as Ag[7], Al[8], Zn[9], Cu[10], Ti[11], N&O[12] doped into the conventional GST. Especially, SnTe doping GST exhibits a faster crystallization speed than GST[13], which is favorable to the operation speed of PCM. This improvement attributes to a weaker bonding strength of Sn–Te (359.8 kJ·mol⁻¹) compared with the Ge–Te bond (397 kJ·mol⁻¹)[13]. Recently, Sb-Se was proposed for low power PCM due to its low thermal conductivity and low melting point[14]. It is shown that Sb₂Se has higher T_c (198°C) and 10-year life time temperature(107°C))[15] than GST, suggesting a better thermal stability for

PCM. In addition, Sb₂Se shows a faster crystallization since Sb-rich phase-change materials have a growth-dominated crystallization behavior rather than a nucleation-dominated one(GST)[16]. From this point of view, Sb₂Se-GST materials will possess the characteristics of better thermal stability as well as faster crystallization speed. Therefore, it is worthwhile to incorporate Sb₂Se into GST and to investigate structural, thermal, optical, and electrical properties.

2. Experimental

Sb₂Se-GST films were deposited on Si/SiO₂ substrate at room temperature via co-sputtering Sb₂Se and GST alloy targets. The background pressure was 1.6^{-4} Pa, and chamber pressure became 0.3 Pa during the film deposition. The dc power on the Sb₂Se target ranged from 3 to 13 W, while the RF power on the GST target ranged from 5 to 50 W for optimizing Sb₂Se content. The composition of the film was determined by energy dispersive spectroscopy (EDS). The samples in this study can be denoted by Ge₂₅Sb₂₃Te₅₀Se₂, Ge₂₁Sb₂₉Te₄₁Se₉, Ge₁₆Sb₃₆Te₂₉Se₁₉ and Ge₄Sb₅₂Te₉Se₃₅. The phase structures of the Sb₂Se doping GST thin films were analyzed by the x-ray diffraction (XRD) technique (Bruker D2 PHASER diffractometer) in the 2 θ range from 10° to 60°. The sheet resistance of the Sb₂Se-GST film was in situ measured using a four-point probe in a homemade vacuum chamber. The optical transmission in the spectral range 300–2500 nm was obtained by a Perkin-Elmer Lambda 950 UV–VIS–NIR spectrophotometer. The absorption coefficient (α) was calculated by a general relationship:

$$a = -(1/d)\ln(T),\tag{1}$$

where d and T are the thickness of the film and transmission, respectively. The optical band gap (E_{opt}) is deduced from the expression:

$$\alpha(v) \cdot hv = B(hv - E_{opt})^2 \ [17], \tag{2}$$

where *B* and hv are a constant and the energy of the incident photon, respectively. Raman spectroscopy was employed to study the changes in chemical bonds of Sb₂Se-GST film. The microstructure was analyzed by transmission electron microscope (TEM).

3. Results and discussion

The sheet resistance versus temperature (R-T) at a heating rate of 40°C/min for different samples is shown in Fig. 1(a). The resistance of all the films initially decreases slowly with the increasing temperature due to the heat active carrier for hopping conduction. The resistance decreases suddenly to over one order of magnitude when the amorphous-to-crystalline transition occurs. A steep decrease of resistance around the crystallization temperature can be observed for the Sb₂Se-doped GST films. The crystallization temperature (T_c) was determined from the minimum of the derivative of R-T curve. T_{cs} of $Ge_{25}Sb_{23}Te_{50}Se_2$, $Ge_{21}Sb_{29}Te_{41}Se_9$, Ge₁₆Sb₃₆Te₂₉Se₁₉ and Ge₄Sb₅₂Te₉Se₃₅ are listed in Table 1, which is higher than that of GST(about 170°C). The addition of Sb₂Se will form the nano-mixture phase which brings a larger number of extra bonds into the GST. And it will cause a disturbance to the crystallization behavior of the whole system. Thus, T_c of Sb₂Se-GST film increases with the concentration of Sb₂Se. The slope of R-T curve around T_c reflects on the crystallization speed of phase change material which is the crucial factor for the operation speed of PCM. It is shown that the absolute value of slope becomes smaller with increasing Sb₂Se concentration when Se atomic percentage is less than 19%, suggesting the sluggish crystallization of GST with a certain amount of Sb₂Se. As the Se atomic percentage increase to 35%, the absolute value of slope achieves maximum and

the resistance drop become the fastest, as shown in Fig. 1(a). From this point of view, the $Ge_4Sb_{52}Te_9Se_{35}$ has the shortest crystallization time among studied compositions as well as GST. It is noted that resistance undergoes the second drop to a more stable low level for $Ge_{25}Sb_{23}Te_{50}Se_2$ and GST due to the second structure transition. And the transition was suppressed when Se atomic percentage is larger than 9%. For all compositions, about five orders of magnitude of the resistance contrast between amorphous state and crystalline state is helpful in achieving a high On/OFF ratio[18].

Composition(at.%)	T (°C)	$E(\mathbf{a}\mathbf{V})$	
Ge Sb Te Se	$I_{c}(C)$	$L_{a}(ev)$	
25 23 50 2	76	2.31	
21 29 41 9	58	1.77	
16 36 29 19	101	2.78	
4 52 9 35	100	2.54	
$ \begin{array}{rrrrrrrrrrrrrrrrrrrrrrrrrrrrrrrrrrrr$	76 58 101 100	2.31 1.77 2.78 2.54	

Table 1 the crystallization parameters of Ge-Sb-Te-Se films

Thermal stability of as-deposited amorphous is an important factor to forecast the data retention of PCM devices. The failure time is defined as the time when the resistance decrease to half of its initial value at a specific temperature[19]. The data retention of as deposited amorphous film is obtained by the Arrhenius equation[20]:

$$t = Aexp\left[\frac{E_{\alpha}}{K_{b}T}\right],\tag{3}$$

where t, A, E_{α} and K_b are the failure time, a proportional time constant, the activation energy for crystallization and Boltzmann's constant, respectively. The Arrhenius plot of 10-year data retention for as-deposited amorphous Sb₂Se-GST films is given by Fig. 1(b). It is shown that $Ge_{25}Sb_{23}Te_{50}Se_2$ and $Ge_{21}Sb_{29}Te_{41}Se_9$ have poor 10-year data retention capability (below 76°C) in

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Fig. 1(b), which is not satisfied for use in PCM device. The data retention can be improved by the Se atomic percentage is larger than 9% which possesses 10-year data retention at above 100°C as well as a large activation energy for crystallization (above 2.54eV), as shown in Fig. 1(b). Apparently, Sb₂Se-GST film with Se atomic percentage is above 9% owing better thermal stability and larger crystallization activation energy that are more suitable for PCM devices.

The crystalline structure of Sb₂Se-GST films were studied by x-ray diffraction measurement. There are two weak diffraction peaks for Ge₂₅Sb₂₃Te₅₀Se₂ and Ge₂₁Sb₂₉Te₄₁Se₉ films annealed at 170°C, as shown in Fig. 2(a). This phenomenon can be explained by the low T_c of them. The characteristic peaks appear for Ge₁₆Sb₃₆Te₂₉Se₁₉ and Ge₄Sb₅₂Te₉Se₃₅ film annealed at 200°C(see Fig. 1(b), suggesting both of them being crystallized. T_{cs} are about 200°C, which is consistent with *R*-*T* results. It is also shown that Ge₄Sb₅₂Te₉Se₃₅ crystallizes into Sb₂Se₃, Sb and GST phase exhibiting a single FCC GST structure. At 260°C, Ge₄Sb₅₂Te₉Se₃₅ exhibits stronger diffraction intensity than other samples, as shown in Fig. 2(c), suggesting its higher degree of crystallinity. The fine crystallinity in the film is related to the low disorder level which leads to high carrier density as a result of more delocalized electronic states. That is why the resistance of Ge₄Sb₅₂Te₉Se₃₅ film is lower than those of other compositions at 260°C(see Fig 1(a)). With the annealing temperature increasing to 350°C, the crystalline structure of Ge₂₅Sb₂₃Te₅₀Se₂ film transferred from FCC into hexagonal phase, as shown in Fig. 2(d). It is in good agreement with the second-step resistance of $Ge_{25}Sb_{23}Te_{50}Se_{2}$ film in *R-T* curve. The FCC and hexagonal phases coexists in Ge₂₁Sb₂₉Te₄₁Se₉ film at 350°C. As the Se atomic percentage increased to 19%, the precipitation of Sb₂Se₃, Sb, and GST crystalline phases is observed at 350°C, as shown in Fig.

1(d). According to the Scherrer's equatioin[21] the mean crystallite size is inversely proportional to the full width at half maximum (FWHM) of the diffraction peak. It is clearly observed that the FWHM of the peak with maximum intensity increases with the concentration of Sb₂Se, suggesting the addition of Sb₂Se suppressing the grain growth. The Ge₄Sb₅₂Te₉Se₃₅ has the minimum crystallite size, which will produce more grain boundaries. As a result, it has relatively high resistance at 350°C(see Fig. 1(a)) due to more carrier scatters compared to other samples.

The spectroscopic ellipsometer can be used to determine E_{opt} of the materials. Transmission spectra and plot of $(\alpha h v)^{\frac{1}{2}}$ versus hv are for amorphous Ge₄Sb₅₂Te₉Se₃₅ film. For higher values (α >10⁴ cm⁻¹), the absorption coefficient α yields the power part which obeys the Tauc et al[22] and Davis and Mott relation[23, 24] for the allowed indirect transition:

$$(\alpha h \nu)^{\frac{1}{2}} = B^{\frac{1}{2}} (h \nu - E_{opt}), \tag{4}$$

where $B^{\frac{1}{2}}$, *h*, *v* and E_{opt} are a Tauc parameter of the investigated substance, Plank's constant, frequency and the optical band gap, respectively. As shown in Fig. 3, the E_{opt} and slope quantities $B^{1/2}$ of amorphous $Ge_4Sb_{52}Te_9Se_{35}$ film calculated from the Tauc's plot are 0.71eV and 796.4cm^{-1/2}eV^{-1/2}, which are higher than those of GST (0.69eV and 714.6 cm^{-1/2}eV^{-1/2})[25]. The widening of band gap in amorphous materials has fundamental importance due to the presence of trap states, which plays an important role in switching by filling up the charge carriers to become conductive [26]. At the same time, a higher value of $B^{1/2}$ indicates more disorder, and consequently increase On/OFF ratio[27]. It indicates the addition of amounts of Sb₂Se into GST is favorable to enhance the switching properties.

The vibration mode of bonds in crystalline phase was analyzed using Raman spectroscopy.

Fig. 4(a) shows Raman spectra of GST and Ge₄Sb₅₂Te₉Se₃₅ films annealed at 200°C . For GST film, the broad Raman band centered at 105 cm⁻¹ is associated with the A₁ mode of GeTe₄ corner-sharing tetrahedral and a broad band at 155 cm⁻¹ is related to Sb–Te bonds' vibrations in SbTe₃ units[28]. The main feature of the Raman spectrum for the crystallized Ge₄Sb₅₂Te₉Se₃₅ is the existence of two overlapping band with two peaks at about 143 and 163cm⁻¹, which are believed to originate from the SbTe₃ pyramids vibrational modes and Sb-Sb bonds vibration modes of [Sb₂Se-SbSe₂], respectively. As the annealing temperature increases to 350°C, the Raman spectrum of both samples changed more or less, as shown in Fig. 4(b). The original peak at 163cm⁻¹ shifted to higher frequency (about 171cm⁻¹), and the other peak remained its position for GST film. It is indicated that the FCC-to-HEX phase transition of GST is ascribed to the atomic arrangement in SbTe₃ units rather than GeTe₄ tetrahedral. For Ge₄Sb₅₂Te₉Se₃₅ film, the position of peaks keeps motionless and substantial amplitude increases for the peak at 155 cm⁻¹ due to the high degree of crystallization. It is suggested that the Sb₂Se phase suppressed significantly the second phase-transition of GST phase for Ge₄Sb₅₂Te₉Se₃₅ film, which is good agreement with XRD result.

The bond environment of $Ge_4Sb_{52}Te_9Se_{35}$ film was investigated by X-ray photoelectron spectroscopy. The core level spectra of Se 3d, Sb 3d and Te 3d are plotted in Fig. 5(a)-5(c). The binding energy of Se 3d for $Ge_4Sb_{52}Te_9Se_{35}$ results from Sb-Se peak centered at 53.9eV[29] which is lower than Se-Se homopolar binding energy of pure Se. After Sb₂Se doping into GST, the peak positions of both Sb 3d and Te 3d spectra shift to higher binding energy for $Ge_4Sb_{52}Te_9Se_{35}$ compared with GST, As shown in figure 5(b) and 5(c). It has been reported that

the binding energy of an element increases with increasing electronegative of neighbor bonding atom [6, 30]. The electronegativity of Se, Te, Sb and Ge are 2.55, 2.1, 2.05 and 2.01 respectively[31]. Therefore, Se has formed the chemical bonds with others. It indicates that the incorporation of Sb₂Se into GST suffers from atomic reconfiguration to change the bonding state. The bonding recombination may account for the suppression of the phase transformation from FCC to hexagonal as shown in Fig. 2(d).

The microstructure of Ge₄Sb₅₂Te₉Se₃₅ was observed by TEM. The samples were fabricated on carbon membrane substrates. TEM image of Ge₄Sb₅₂Te₉Se₃₅ film annealed at 260°C. The black particles with a size of several tens of nanometers are uniformly distributed in the film in Fig. 6(a). The dispersive dots along diffraction ring can be observed in the selected area electron diffraction (SAED) pattern (see Fig. 6 (b)), suggesting high degree of crystallization. Figure 6(c) shows the high-resolution TEM image of $Ge_4Sb_{52}Te_9Se_{35}$ film. The main feature of the black particles was confirmed to be the polycrystalline structure of embedded Sb₂Se, Sb and GST crystallites. The polycrystalline morphology composed of a large number of crystallites with different size smaller than 60 nm, which is characteristic of the nucleation dominated mechanism. There are main two crucial factors to influence the crystalline speed for nucleation dominated mechanism. One is the large nucleation probability which will increase the number of crystal nuclei to promote the fast crystallization. The large differences in electronegativity of Ge₄Sb₅₂Te₉Se₃₅ may serves as a nucleation drive to increase the nucleation probability. The other is the small grain size. Compared with the large grain, it will shorten time when nuclei just grow up to a small grain to complete crystallization. Thus, Ge₄Sb₅₂Te₉Se₃₅ shows fast crystallization

velocity.

4. Conclusions

In summary, phase change properties of Sb₂Se-GST film were systematically studied. The crystallization temperature of Sb₂Se-GST increases with increasing Sb₂Se content. The data retention ability of amorphous Sb₂Se-GST film can be improved when with the Se atomic percentage is larger than 19%. Only single crystalline phase of FCC could be observed upon annealing for Sb₂Se-GST film with Se atomic percentage larger than 9%. The large resistivity of the crystalline Sb₂Se-GST film is beneficial to reduce the write current. Compared with GST, Ge₄Sb₅₂Te₉Se₃₅ film shows better thermal stability, wider band gap and faster crystallization, suggesting a potential candidate for PRAM.

Acknowledgements

This work was supported by the National Natural Science Foundation of China (Grant Nos. 61306147 and 61377061), Ningbo municipal Natural Science Foundation of China (Grant No. 2014A610121), and Natural Science Foundation of Zhejiang Province, China (Grant No. LQ15F040002), and sponsored by K. C. Wong Magna Fund in Ningbo University.

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FIG.1. (a) Sheet resistance as a function of temperature for pure and Sb₂Se-doped GST films. (b) Failure time versus reciprocal temperature for Sb₂Se-doped GST films.



FIG.2. XRD patterns of Sb₂Se-GST films (a) 170°C, (b) 200°C, (c) 260°C, and (d) 350° C, respectively.



FIG.3. Plots of $(ahv^{1/2})$ vs hv for as deposited Ge₄Sb₅₂Te₉Se₃₅ film; Inset shows





FIG.4. Raman spectra of GST and Ge₄Sb₅₂Te₉Se₃₅ films annealed at (a) 200°C and (b)

350°C.



FIG.5. XPS spectra for crystalline GST and $Ge_4Sb_{52}Te_9Se_{35}$ films: (a) Se 3d, (b) Sb 3d,

and (c) Te 3d.





at 260°C, respectively.



Ge₄Sb₅₂Te₉Se₃₅ exhibits stronger diffraction intensity than other samples, as shown in Fig. (a), suggesting its higher degree of crystallinity. The fine crystallinity in the film is related to the low disorder level which leads to high carrier density as a result of more delocalized electronic states. As the Se atomic percentage increased to 19%, the precipitation of Sb₂Se₃, Sb, and GST crystalline phases is observed at 350°**C**, as shown in Fig. (b). And the phase transition from face-centered-cubic to hexagonal phase was suppressed. The main feature of the black particles was confirmed to be the polycrystalline structure of embedded Sb₂Se, Sb and GST crystallites as shown in Fig. (c). The polycrystalline morphology composed of a large number of crystallites with different size smaller than 60 nm. Compared with the large grain, it will shorten time when nuclei just grow up to a small grain to complete crystallization. Thus, Ge₄Sb₅₂Te₉Se₃₅ shows fast crystallization velocity.